

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

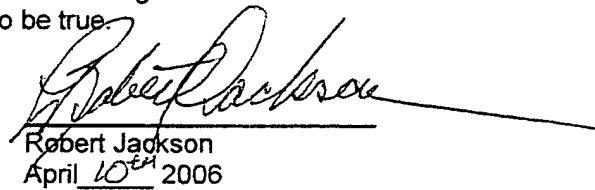
## Declaration Under 37 C.F.R. 1.131

Atty. Docket No.  
FOC1100-1

Applicant <b>Robert Jackson</b>	
Application Number <b>10/038,745</b>	Date Filed <b>01/02/2002</b>
Title <b>Method and System for On-Site Generation and Distribution of a Process Gas</b>	
Group Art Unit <b>1754</b>	Examiner <b>Nguyen, Ngoc Yen M.</b>
Confirmation Number: <b>2978</b>	

1. I, Robert Jackson, am the sole inventor of the invention described and claimed in the above-referenced patent application.
2. The invention claimed in the above-referenced patent application was conceived at least as early as November 29, 2000.
3. Attached hereto as Declaration Exhibit A is a copy of a presentation dated November 29, 2000. This presentation is saved as "11 29 2000 Semiconductor Fluorine Plant670" on Fluorine On Call's ("FOC") computer system and was generated by FOC at least as early as November 29, 2000. Slides 2 and 3 of the presentation show parallel HF traps coupled to fluorine generation cells and a filter downstream of the HF traps. Slide 3 further shows a low pressure buffer and compressor downstream of the HF traps. Slides 2 and 3 also illustrate various flow paths provided by manifolds. Slide 4 of the presentation describes that the HF traps are NaF traps and that switching occurs.
4. On November 26, 2001, a provisional patent application was filed disclosing the invention.
5. Declarant acknowledges that willful false statements and the like are punishable by fine or imprisonment, or both (18 U.S.C. 1001) and may jeopardize the validity of the application or any patent issuing thereon.

I, Robert Jackson, aver that all statements made of my own knowledge are true and all statements made on information and belief are believed to be true.



Robert Jackson  
April 10<sup>th</sup> 2006

**DECLARATION EXHIBIT A**



**FOC**

**Fluorine On Call, Ltd.**

PLC/Instrumentation  
and Power Distribution

Cell 1 1000A PSU

125 Litre Fluorine  
Buffer Tank

Touch  
Screen

Cell 1  
Cooling  
System

Fluorine  
Compression  
System

Fluorine  
Generator  
No. 1

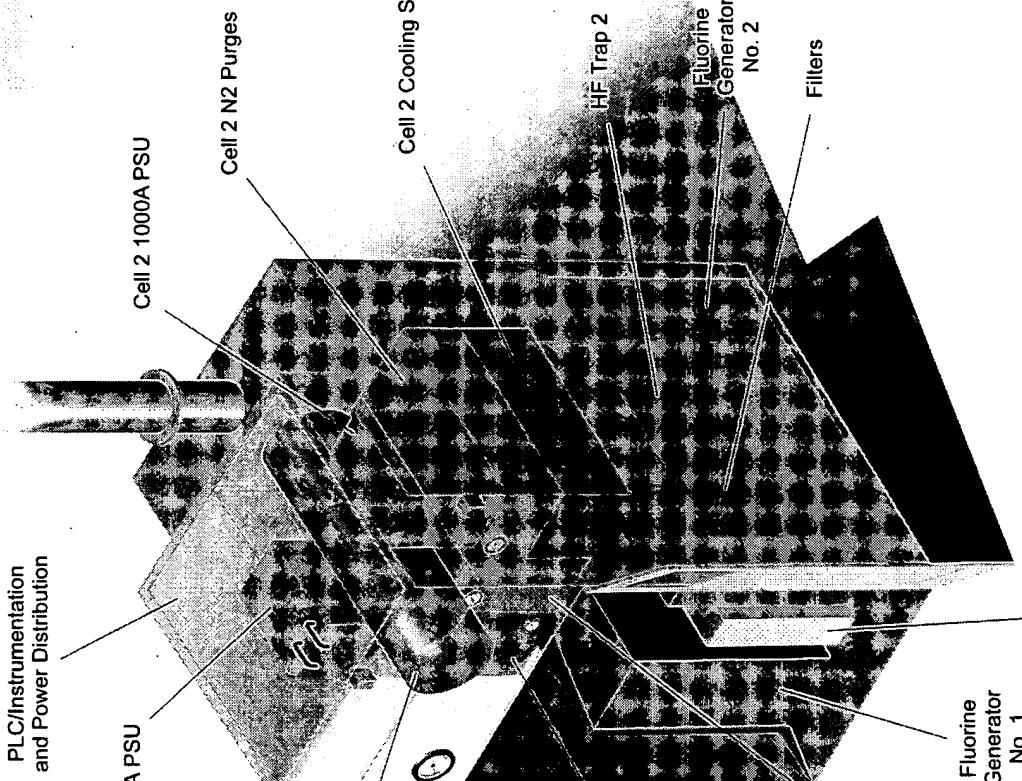
HF Trap 1

Cell 2 Cooling Systems

HF Trap 2

Fluorine  
Generator  
No. 2

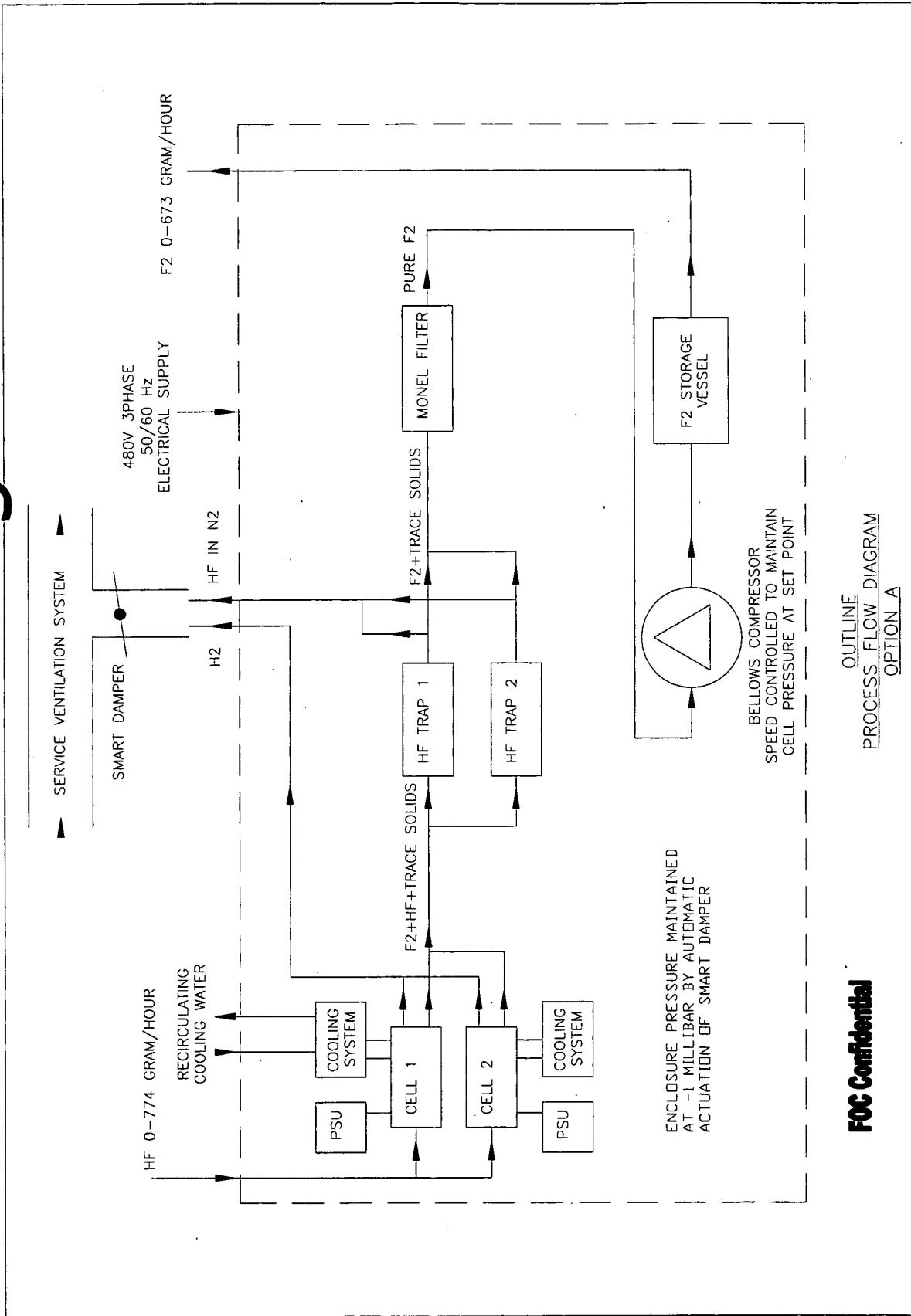
Filters



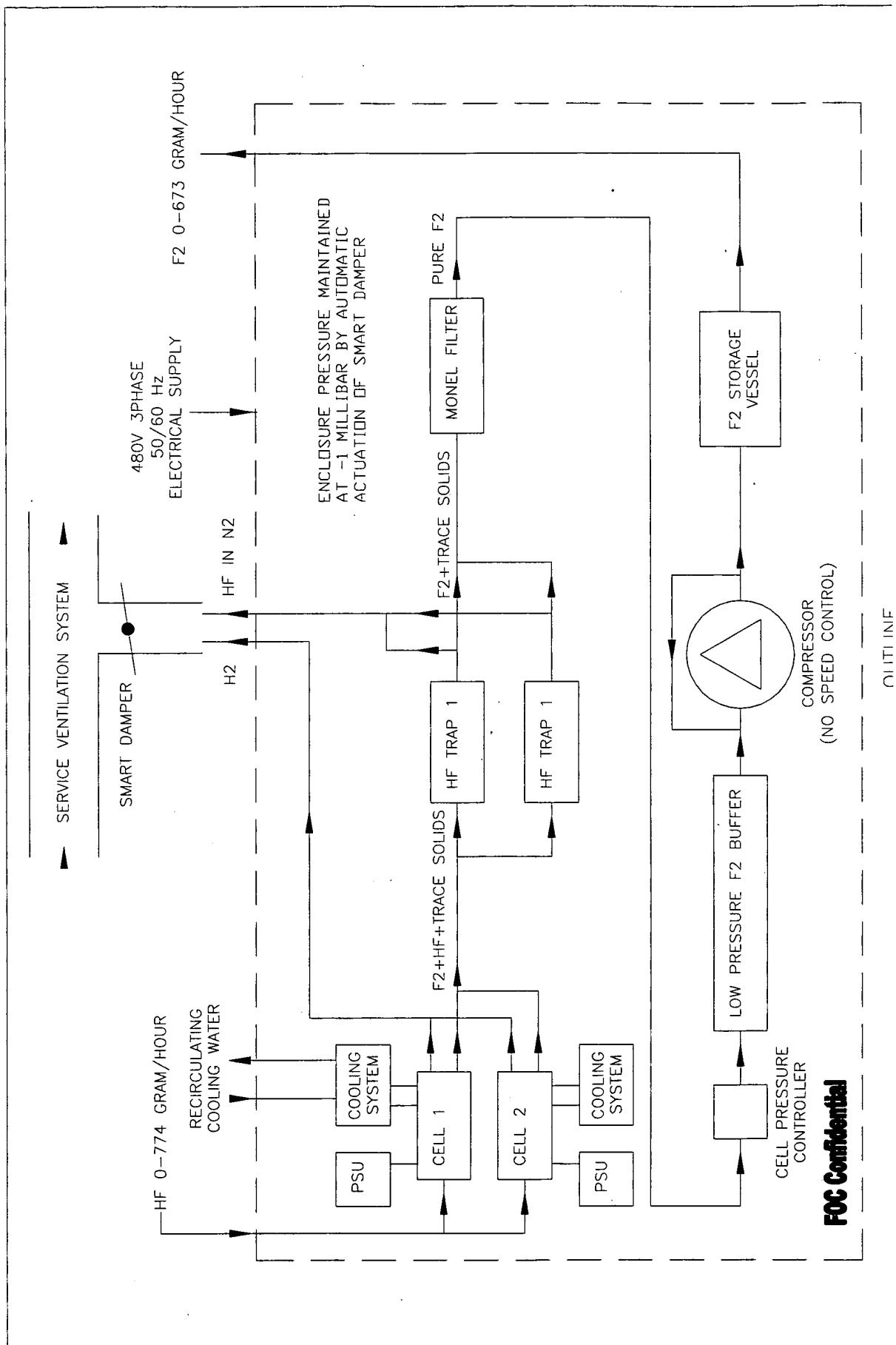
**Semiconductor Packaged Fluorine Cell**

**FOC Confidential**

# Process Flow Diagram



# PROCESS Flow Diagram



# Design Concepts

## Sodium Fluoride Traps

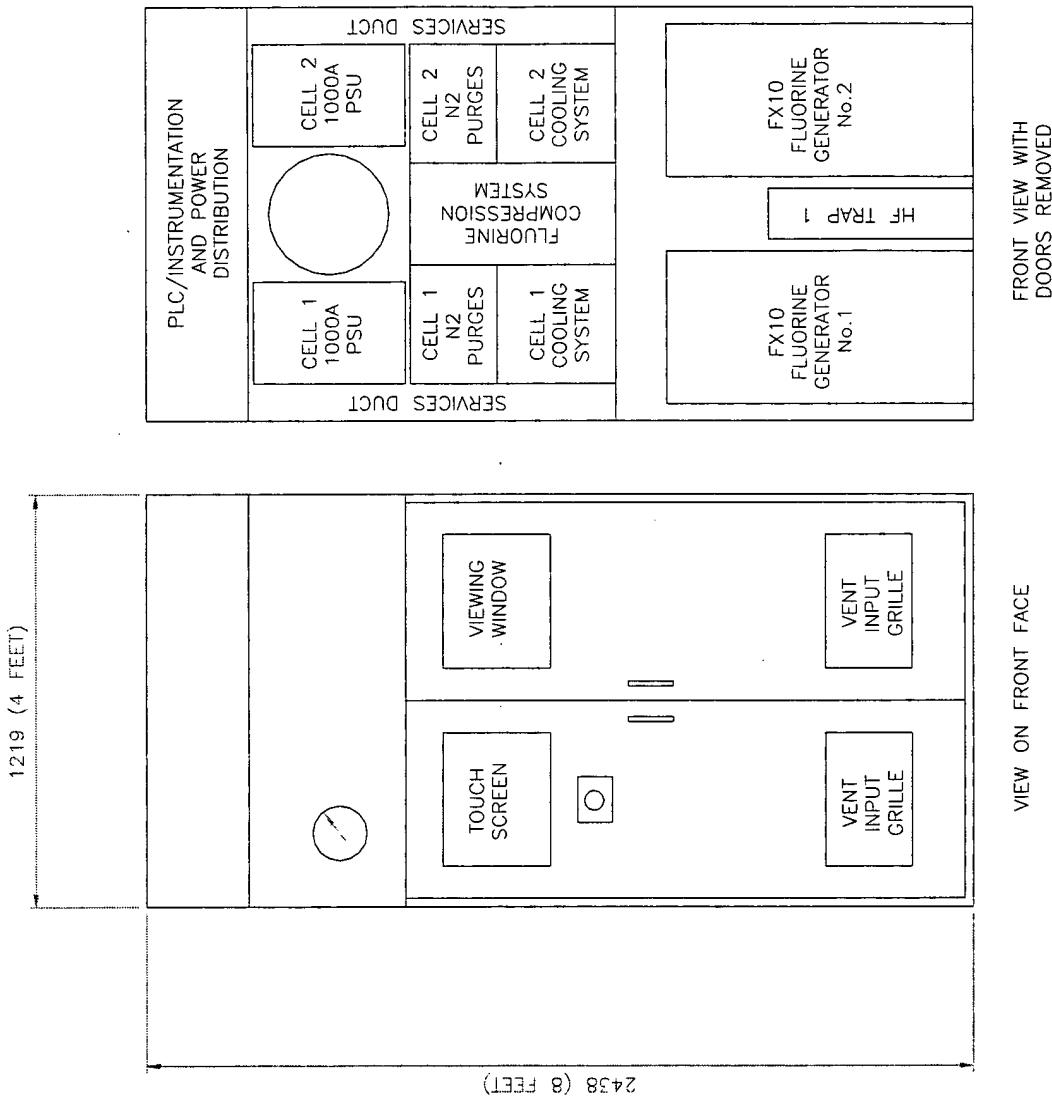
- Duty and stand-by design
- PLC controlled automated switch-over
- PLC controlled automated regeneration capability
- Proven high efficiency absorption path design
- PLC monitoring of upcoming change-out and service requirements
- Low metallic impurities, Monel construction, Stainless steel jacketed
- Simple MTTR design

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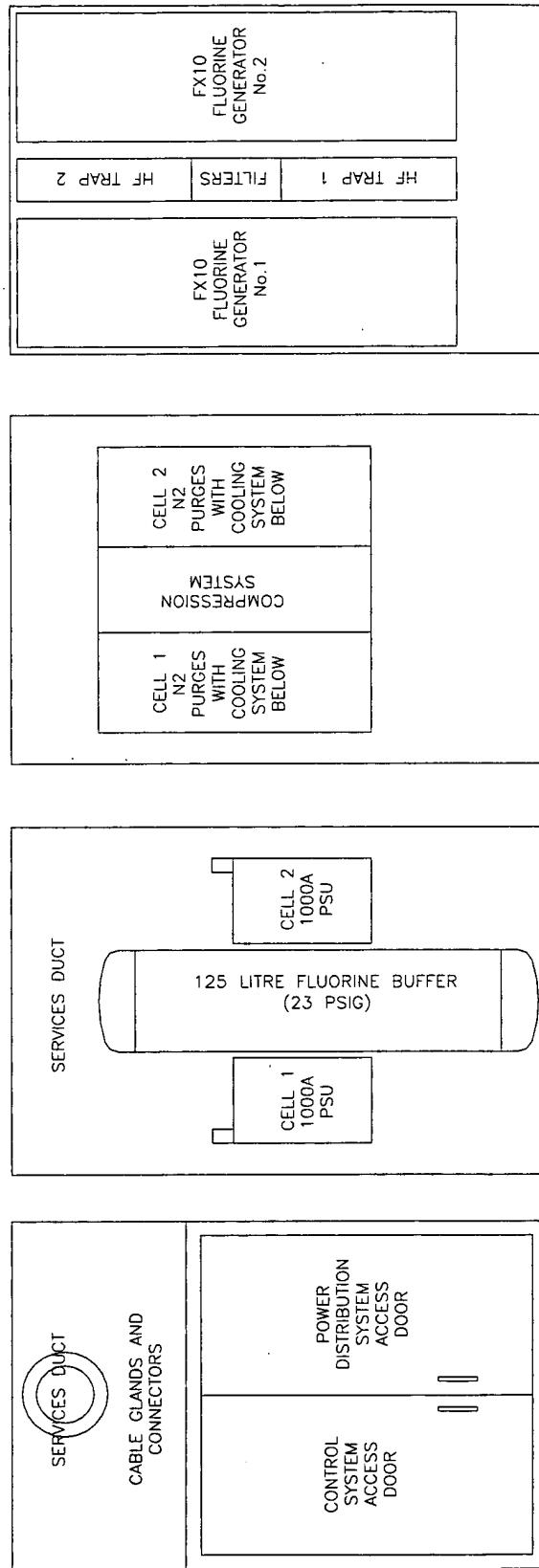
**Fluorine On Call, Ltd.**

# Conceptual Component Layout (1)



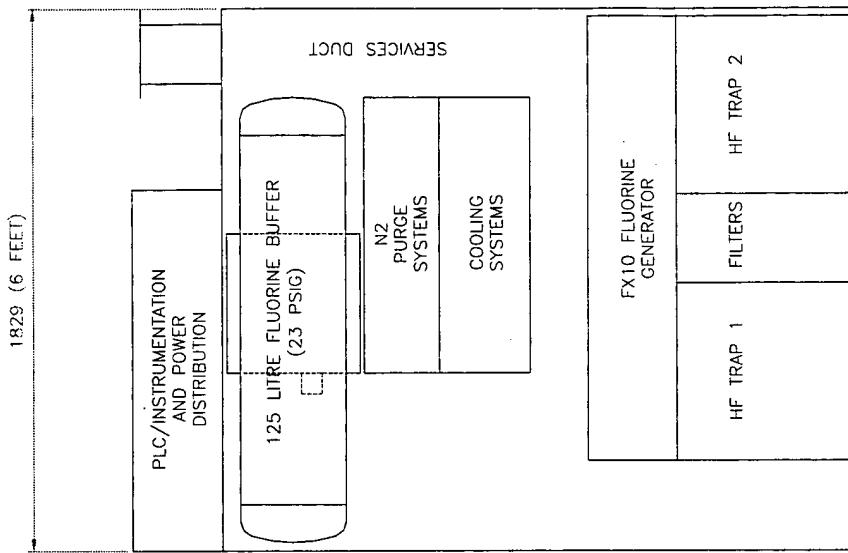
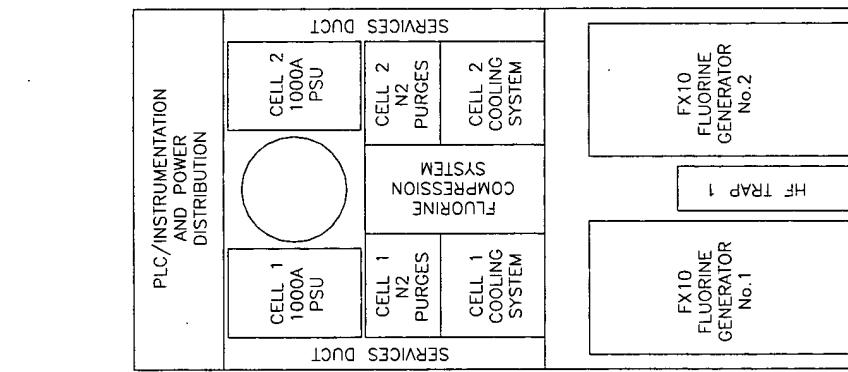
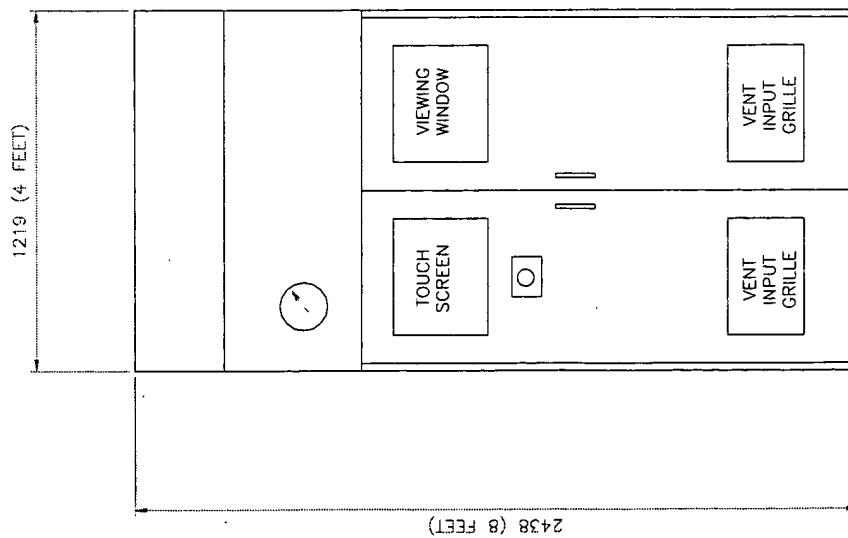
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# Conceptual Component Layout (2)



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# Layout (3)



SECTIONAL SIDE VIEW

FRONT VIEW WITH DOORS REMOVED